

Abstract of the Disclosure

A defect source identifier that provides information used to identify a source of a defect on a substrate, which defect source identifier includes a LotRoute database generation process and a LotRoute database access process, wherein the

- 5 LotRoute database generation process includes a software application that runs on a server and that, in response to user input, defines a wafer route including wafer route information, and associates the wafer route with any one of a number of entities; and the LotRoute database process includes a software application that runs on the server and that, in response to input from the defect source identifier, retrieves the wafer route
- 10 information using an identifier of one of the entities.

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